ABSTRACT OF THE DISCLOSURE

Transfer method of a thin layer (18) of a source substrate (10) on a target substrate (30) including the following steps:

a) implantation of ions or gas species in the source substrate so as to form there a zone (16), called splitting, which delimits said thin layer (18) in the substrate source,

b) transfer of the source substrate on the target support and the interlocking of the thin layer with the target support,

c) separation of the thin layer (18) from the source substrate (10) along the splitting zone,

in conformance with the invention, the method includes prior to step b):

- overembrittlement of the splitting zone (16) caused by heat treatment and/or exerting mechanical forces on the source substrate.

Figures 4 and 5